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RESPONSE UNDER 37 CFR 1.116
EXPEDITED PROCEDURE
EXAMINING GROUP 2851

03560.002558

PATENT APPLICATION

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:)
Yuji SUDOH et al.)
Application No.: 09/532,022)
Filed: March 21, 2000)
For: EXPOSURE APPARATUS AND A)
DEVICE MANUFACTURING METHOD :
WHICH KEEP TEMPERATURE OF A)
DIAPHRAGM OF A PROJECTION :
OPTICAL SYSTEM SUBSTANTIALLY)
CONSTANT :
Examiner: H. Nguyen
Group Art Unit: 2851
August 3, 2004

Mail Stop AF
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Do not enter.
8/16/04
HN

AMENDMENT AFTER FINAL ACTION

Sir:

In response to the final Official Action dated May 7, 2004, please amend the
above-identified application as follows, pursuant to 37 C.F.R. § 1.116: